

**SPECIFICATION****TITLE OF INVENTION****METHOD FOR TOOLMATCHING AND TROUBLESHOOTING A PLASMA  
PROCESSING SYSTEM****STATEMENT OF RELATED APPLICATION**

**[0001]** The present application is a continuation-in-part of U.S. Patent  
Application Serial No. 10/341,913, filed January 13, 2003, <sup>now Pat. No. 6,873,114</sup> in the name of inventors  
Armen Avoyan and Seyed Jafar Jafarian-Tehrani, entitled "Method for toolmatching and  
troubleshooting a plasma processing system", commonly assigned herewith. U.S. Patent  
Application Serial No. 10/341,913, filed January 13, 2003, claims the benefit of U.S.  
Provisional Patent Application Serial No. 60/414,108, filed September 26, 2002, in the  
name of inventors Armen Avoyan and Seyed Jafar Jafarian-Tehrani, commonly assigned  
herewith.

**FIELD OF THE INVENTION**

**[0002]** The present invention relates to the fabrication of materials such as  
electronic devices in plasma processing system. More particularly, the present invention  
relates to a method and system for verifying the operation of a plasma processing system.